

| | | | | |
|-----------------------------------|---------------------------------------|--|---|-------------|
| Notice of References Cited | Application/Control No. 10/696,994 | | Applicant(s)/Patent Under Reexamination CURRIE ET AL. | |
| | Examiner William M. Brewster | | Art Unit 2823 | Page 1 of 1 |

U.S. PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Name | Classification |
|---|---|--|-----------------|----------------------|----------------|
| X | A | US-2004/0040493 | 03-2004 | Vineis et al. | 117/089 |
| X | B | US-2004/0031979 | 02-2004 | Lochtefeld et al. | 257/233 |
| X | C | US-2002/0171077 | 11-2002 | Chu et al. | 257/19 |
| X | D | US-6,838,728 | 01-2005 | Lochtefeld et al. | 257/325 |
| X | E | US-6,831,292 | 12-2004 | Currie et al. | 257/19 |
| X | F | US-6,680,496 | 01-2004 | Hammond et al. | 257/192 |
| X | G | US-4,764,248 | 08-1988 | Bhattacharjee et al. | 438/439 |
| | H | US- | | | |
| | I | US- | | | |
| | J | US- | | | |
| | K | US- | | | |
| | L | US- | | | |
| | M | US- | | | |

FOREIGN PATENT DOCUMENTS

| * | | Document Number Country Code-Number-Kind Code | Date MM-YYYY | Country | Name | Classification |
|---|---|--|-----------------|---------|------|----------------|
| | N | | | | | |
| | O | | | | | |
| | P | | | | | |
| | Q | | | | | |
| | R | | | | | |
| | S | | | | | |
| | T | | | | | |

NON-PATENT DOCUMENTS

| * | | Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages) |
|---|---|---|
| | U | Stanley Wolf Ph.D. and Richard N. Tauber Ph.D. in Silicon Processing for the VLSI Era, Volume 1: Process Technology, Lattice Press, 1986, 99. 182-3, 307-8. |
| | V | |
| | W | |
| | X | |

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.